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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:) Examiner: Not Yet Assigned
TAKAO YONEHARA, et al.) Group Art Unit: 2871
Application No.: 10/059,171)
Filed: January 31, 2002)
For: METHOD OF MANUFACTURING) August 15, 2002
DISPLAY DEVICE)

RECEIVED

AUG 21 2002
PC 2800 MAIL ROOM

Commissioner for Patents
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed below and on the enclosed Form PTO-1449. Copies of the below-listed documents are enclosed.

- (1) European Patent 1,122,794
- (2) European Patent 858,110
- (3) European Patent 849,788
- (4) Shimoda, T., et al., "Surface Free Technology By Laser Annealing (SUFTLA)", International Electron Devices Meeting 1999. IEDM. Technical Digest. Washington, DC, Dec. 5 to 8, 1999, New York, NY: IEEE, US, August 1, 1999 (1999-08-01), pages 289 to 292, XP000933199 ISBN: 0-7803-5411-7.
- (5) Japanese Patent 11-316397

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231 on

August 15, 2002

(Date of Deposit)

Carole A. Quinn, Reg. No. 39,000

(Name of Attorney for Applicant)

[Signature]

(Date of Signature)

- (6) U.S. Patent 6,190,937
- (7) U.S. Patent 6,222,513
- (8) U.S. Patent 6,258,698
- (9) U.S. Patent 6,306,729
- (10) U.S. Patent 6,331,208
- (11) U.S. Patent 6,342,433
- (12) U.S. Patent 6,382,292

Documents (1) to (4) were cited during prosecution of a European counterpart application to the above-identified U.S. Application. A copy of the European Search Report, which is dated June 7, 2002, is also enclosed.

Document (5) is discussed in the subject application, commencing at page 6, line 3, and is believed to be pertinent for the reasons noted therein. Document (7) issued from U.S. Application No. 09/037,767, which is believed to be a U.S. counterpart application to JP 11-316397 (i.e., Document (5) above). An English language abstract of Document (5) is also enclosed.

The Examiner's attention is also directed to the following U.S. application, which is commonly assigned with the subject application:

| <u>Application No.</u> | <u>Filing Date</u> | <u>Group Art Unit</u> |
|------------------------|--------------------|-----------------------|
| 09/586,887 | 06/05/2000 | 2825 |

In accordance with 37 C.F.R. § 1.98(a)(2)(iii), a copy of the application, including specification, claims and drawings, is enclosed.

Finally and in an Information Disclosure Statement (IDS) filed concurrently with the subject application on January 31, 2002, the Examiner's attention was directed to two U.S. applications also filed on January 31, 2002, listed below.

| <u>Application No.</u> | <u>Attorney Docket No.</u> | <u>Filing Date</u> | <u>Group Art Unit</u> |
|------------------------|----------------------------|--------------------|-----------------------|
| 10/059,116 | 00862.022497 | 01/31/2002 | 2814 |
| 10/059,144 | 00862.022498 | 01/31/2002 | 2871 |

In accordance with 37 C.F.R. § 1.98(a)(2)(iii), copies of the applications, including specification, claims and drawings, were submitted with the January 31, 2002 IDS. Since these applications had not yet been assigned application serial numbers, they were identified in the January 31st IDS by their corresponding attorney docket numbers. Applicants now provide the application serial numbers and group art unit assignments corresponding to these two applications. In addition and for the Examiner's convenience, an additional copy of the specification, claims and drawings of each of these applications is provided herewith.

Inasmuch as this application has not yet received a first Office Action on the merits, it is believed that this Information Disclosure Statement is timely. See 37 C.F.R. §1.97(b)(3). Accordingly, the Examiner is urged to study this information in its entirety and to form an independent determination of the materiality of the information to the claimed invention. Additionally, the Examiner is requested to indicate that this information has been considered by initialing the appropriate portion of Form PTO-1449.

Applicants' undersigned attorney may be reached in our Costa Mesa,
California office by telephone at (714) 540-8700. All correspondence should continue to
be directed to our address given below.

Respectfully submitted,



Attorney for Applicants
Registration No. 39,000

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| <p style="text-align: center;">DRAFT</p> <p>FORM PTO 1449 (Modified)</p> <p>U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE</p> <p>AUG 19 2002</p> <p>LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)</p> | | | | ATTY DOCKET NO. 00862.022499 | APPLICATION NO. 10/059,171 | | |
|--|----|--|-------------------|--|--------------------------------------|------------|---------------------------------|
| | | | | APPLICANT TAKAO YONEHARA, et al. | | | |
| | | | | FILING DATE January 31, 2002 | GROUP 2871 | | |
| U.S. PATENT DOCUMENTS | | | | | | | |
| *EXAMINER INITIAL | | DOCUMENT NUMBER | DATE | NAME | CLASS | SUBCLASS | FILING DATE IF APPROPRIATE |
| | | 6,190,937 | 02/20/2001 | Nauagawa, et al. | 438 | 67 | |
| | | 6,222,513 | 03/10/1998 | Howard, et al. | 345 | 84 | |
| | | 6,258,698 | 07/10/2001 | Iwasaki, et al. | 438 | 455 | |
| | | 6,306,729 | 10/23/2001 | Sauaguchi, et al. | 438 | 458 | |
| | | 6,331,208 | 12/18/2001 | Nishida, et al. | 117 | 89 | |
| | | 6,342,433 | 01/29/2002 | Ohmi, et al. | 438 | 455 | |
| | | 6,382,292 | 05/07/2002 | Ohmi, et al. | 156 | 584 | |
| FOREIGN PATENT DOCUMENTS | | | | | | | |
| | | DOCUMENT NUMBER | DATE | COUNTRY | CLASS | SUBCLASS | TRANSLATION YES/NO/ OR ABSTRACT |
| | EP | 1 122 794 | 08/08/2001 | Europe | | | |
| | EP | 858 110 | 08/12/1998 | Europe | | | |
| | EP | 849 788 | 06/24/1998 | Europe | | | |
| | JP | 11-316397 | 11/16/1999 | Japan | G02F | | Abstract |
| OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.) | | | | | | | |
| | | Shimoda, T., et al: "Surface Free Technology By Laser Annealing (SUFTLA)" International Electron Devices Meeting 1999. IEDM. Technical Digest. Washington, DC, Dec. 5-8, 1999, New York, NY: IEEE, US, Aug. 1, 1999 (1999-08-01), pages 289-292, XP000933199 ISBN: 0-7803-5411-7. | | | | | |
| | | | | | | | |
| | | | | | | | |
| EXAMINER | | | | DATE CONSIDERED | | | |

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Sheet 1 of 1